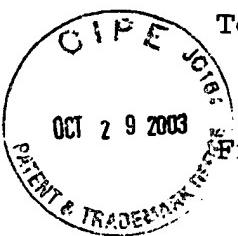


CS-02-012

October 27, 2003



To: Commissioner for Patents  
P.O.Box 1450  
Alexandria, VA 22313-1450  
  
Fr: George O. Saile, Reg. No. 19,572  
28 Davis Avenue  
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/633,131 08/01/03 |  
| Alvaro Maury et al.  
  
ZONE POLISHING USING VARIABLE  
SLURRY SOLID CONTENT  
  
Grp. Art Unit:

#### INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation  
In An Application.

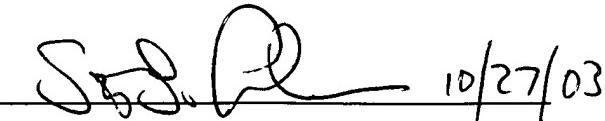
The following Patents and/or Publications are submitted to  
comply with the duty of disclosure under CFR 1.97-1.99 and  
37 CFR 1.56. Copies of each document is included herewith.

#### CERTIFICATE OF MAILING

I hereby certify that this correspondence is being  
deposited with the United States Postal Service as first class  
mail in an envelope addressed to: Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450, on October 27, 2003.

Stephen B. Ackerman, Reg.# 37761

Signature/Date



10/27/03

U.S. Patent 6,398,627 to Chiou et al., "Slurry Dispenser Having Multiple Adjustable Nozzles," describes a slurry dispenser having multiple adjustable nozzles.

U.S. Patent 6,234,877 to Koos et al., "Method of Chemical Mechanical Polishing," discloses a CMP tool with adjacent slurry and diluting solution dispensers.

U.S. Patent 6,106,728 to Iida et al., "Slurry Recycling System and Method for CMP Apparatus," discloses a CMP apparatus.

U.S. Patent 5,658,185 to Morgan, III et al., "Chemical-Mechanical Polishing Apparatus with Slurry Removal System and Method," discloses a CMP apparatus.

Sincerely,



Stephen B. Ackerman,  
Reg. No. 37761

**EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.